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Front Matter: Volume 11352

, "Front Matter: Volume 11352," Proc. SPIE 11352, Optics and Photonics for Advanced Dimensional Metrology, 1135201 (16 April 2020); doi: 10.1117/12.2571284

Event: SPIE Photonics Europe, 2020, Online Only

PROCEEDINGS OF SPIE

Optics and Photonics for Advanced Dimensional Metrology

Peter J. de Groot
Richard K. Leach
Pascal Picart
Editors

6–10 April 2020
Online Only, France

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Published by
SPIE

Volume 11352

Proceedings of SPIE 0277-786X, V. 11352

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

Optics and Photonics for Advanced Dimensional Metrology, edited by Peter J. de Groot, Richard K. Leach, Pascal Picart
Proc. of SPIE Vol. 11352, 1135201 · © 2020 SPIE · CCC code: 0277-786X/20/\$21 · doi: 10.1117/12.2571284

Proc. of SPIE Vol. 11352 1135201-1

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Author(s), "Title of Paper," in *Optics and Photonics for Advanced Dimensional Metrology*, edited by Peter J. de Groot, Richard K. Leach, Pascal Picart, Proceedings of SPIE Vol. 11352 (SPIE, Bellingham, WA, 2020) Seven-digit Article CID Number.

ISSN: 0277-786X
ISSN: 1996-756X (electronic)

ISBN: 9781510634763
ISBN: 9781510634770 (electronic)

Published by

SPIE

P.O. Box 10, Bellingham, Washington 98227-0010 USA
Telephone +1 360 676 3290 (Pacific Time) · Fax +1 360 647 1445
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